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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Wang et al.

Attorney Docket No.: NOVL085/
NVLS-2875

Application No.: 10/785,235

Examiner: UNASSIGNED

Filed: February 23, 2004

Group: 2812

**Title: PLASMA DETERMINING AND
SILANOL CAPPING OF POROUS
DIELECTRIC FILMS**

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the U.S. Postal Service with sufficient postage as first-class mail on March 24, 2005 in an envelope addressed to the Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450.

Signed:

Joyce L. Ferreira

INFORMATION DISCLOSURE STATEMENT

37 CFR §§1.56 AND 1.97(b)

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

The references listed in the attached PTO Form 1449, copies of which are attached, may be material to examination of the above-identified patent application. Applicants submit these references in compliance with their duty of disclosure pursuant to 37 CFR §§1.56 and 1.97. The Examiner is requested to make these references of official record in this application.

This Information Disclosure Statement is not to be construed as a representation that a search has been made, that additional information material to the examination of this application does not exist, or that these references indeed constitute prior art.

This Information Disclosure Statement is: (i) filed within three (3) months of the filing date of the above-referenced application, (ii) believed to be filed before the mailing date of a first Office Action on the merits, or (iii) believed to be filed before the mailing of a first Office Action after the filing of a Request for Continued Examination under §1.114. Accordingly, it is believed that no fees are due in connection with the filing of this Information Disclosure Statement. However, if it is determined that any fees are due, the Commissioner is hereby authorized to charge such fees to Deposit Account 500388 (Order No. NOVLP085).

Respectfully submitted,

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| Att. Docket No. 1449 (Modified) | | Atty Docket No. NOVL085/NVLS-2875 | Application No.: 10/785,235 |
| Information Disclosure Statement By Applicant | | Applicant: Wang et al. | |
| (Use Several Sheets if Necessary) | | Filing Date February 23, 2004 | Group 2812 |

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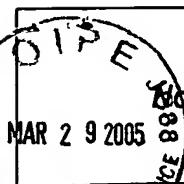
Foreign Patent or Published Foreign Patent Application

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Other Documents

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| | C1 | Humayun et al., "Method For Forming Porous Films By Porogen Removal Combined With In Situ Modification", U.S. Patent No. 10/404,693, filed March 31, 2003, Office Action dated March 15, 2005 |
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| Examiner | | Date Considered |

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.



Notice of References Cited

MAR 29 2005

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NON-PATENT DOCUMENTS

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| | V | |
| | W | |
| | X | |

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.